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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Applicant : Hideaki Yamasaki, et al. Confirmation No. 9914

Serial No. : 10/615,926 Group Art Unit : 1763

Filed : July 10, 2003 Examiner : J. R. Lund

Title: Film-Formation Apparatus and Source Supplying Apparatus Therefor,  
Gas Concentration Measuring Method

**RESPONSE TO RESTRICTION REQUIREMENT**

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

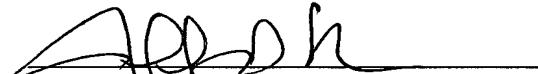
In response to the Restriction Requirement dated April 12, 2005, Applicants hereby elect Claims 1-24 which, as stated in the Office Action, are drawn to a film formation apparatus.

If there are any questions regarding this response or the application in general, a telephone call to the undersigned would be appreciated since this should expedite the prosecution of the application for all concerned.

If necessary to effect a timely response, this paper should be considered as a petition for an Extension of Time sufficient to effect a timely response, and please charge any such fee or any deficiency in fees or credit any overpayment of fees to Deposit Account No. 05-1323 (Docket #010986.52578US).

Respectfully submitted,

April 19, 2005

  
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